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Attachment

503.28546CV9



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: TORII, et al.  
Serial No.: 09/917,912  
Filed: July 31, 2001  
For: METHOD AND APPARATUS FOR PROCESSING  
SAMPLES  
Group: 1756  
Examiner: M. Angebranndt

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JUL 18 2002  
TC 1700

AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

July 15, 2002

Sir:

In response to the Office Action mailed February 14, 2002, please amend the  
above-identified application as follows:

IN THE CLAIMS

Please cancel claims 1-7, 18-26 and 28-65 without prejudice or disclaimer,  
and amend the claims remaining in the application as follows:

SUB  
8.1

8. (Twice Amended) A method of processing a semiconductor sample  
having a laminate comprising at least two adjacent films of at least two different  
metals of different ionization tendencies overlying a semiconductor substrate,  
whereby corrosion could be generated and accelerated due to battery action  
between films of the laminate, including said at least two adjacent films, comprising